



Contribution ID: 60

Type: Oral presentation (by invitation only)

Electropolishing 1300 & 400 MHz SRF copper substrates

Tuesday 31 May 2022 14:27 (9 minutes)

In the frame of the Future Circular Collider (FCC) study, CERN is modelling the copper electropolishing process. The aim is to foresee and optimise the process parameters such as cathode geometry, bath flow and temperature, and minimum potential input, namely on the 400 MHz single cell FCC type cavities and thus contributing in achieving the ultimate performance on the Nb/Cu technology. In this contribution, it'll be presented the current simulation results both on the 1.3 GHz and 400 MHz and on-going benchmarking work.

Authors: BELLINI, Gloria (Ministere des affaires etrangeres et europeennes (FR)); MARQUES ANTUNES FERREIRA, Leonel (CERN); HUGON, Pierre Hippolyte (Universite Montpellier II (FR))

Presenter: BELLINI, Gloria (Ministere des affaires etrangeres et europeennes (FR))

Session Classification: Technology

Track Classification: SRF Programme